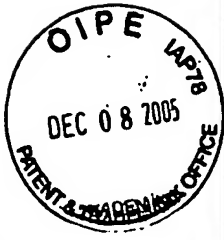


12-09-05

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JW



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: LEE, Ho  
Assignee: SAMSUNG ELECTRONICS CO., LTD.  
Title: CHEMICAL VAPOR DEPOSITION APPARATUS  
Application No.: 10/750,023 Filing Date: December 31, 2003  
Examiner: Jeffrie Robert Lund Group Art Unit: 1763  
Docket No.: AB-1350 US Confirmation No.: 9344

San Jose, California  
December 8, 2005

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P.O. Box 1450  
Alexandria, VA 22313-1450

**AMENDMENT AFTER FINAL OFFICE ACTION**

Dear Sir:

In response to the Final Office Action having a mailing date of October 11, 2005,  
please amend the application as set forth below.

**Claim listing begins on page 2 of this paper.**

**Remarks begin on page 4 of this paper.**

MacPherson Kwok Chen & Heid  
LLP  
1763 Technology Drive, Suite 226  
San Jose, CA 95110  
Telephone: (408) 392-9250  
Facsimile: (408) 392-9262

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